

Abstract of the Disclosure

APPARATUS FOR AND METHOD OF SMOOTHING SUBSTRATE SURFACE

5 An apparatus for smoothing a surface of a rotatably supported substrate includes a
base plate, a block having an extending arm structure and being attached to the base plate
so as to be movable along the surface of the base plate, a roller attached to a tip portion
of the arm structure in a direction perpendicular to the base plate, a mobile member
attached to the arm structure so as to be movable perpendicularly to the axial direction of
10 the roller, a tape-running device attached to the base plate for feeding and taking up a
polishing tape through the roller so as to advance the tape around the mobile member,
and a moving device attached to the arm structure of the block for moving the mobile
member.